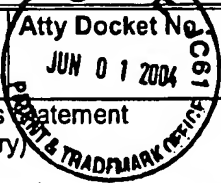



Form PTO-1449 (Modified)		Atty Docket No. P12759C		Serial No.: 10/618,226	
List of Patents and Publications Statement (Use several sheets if necessary)				Applicant: Robert Chau et al.	
				Filing Date: July 11, 2003	



REFERENCE DESIGNATION			U.S. PATENT DOCUMENTS			
Examiner Initials	Document No.	Document No.	U.S. Patent No.	Class	Sub-Class	Filing date if appropriate
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~	AQ	EP1124262 A2	8/16/2001	European Patent Office	H01L	29/51	
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OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
~	AV Smith R.C. et al., "Chemical vapour deposition of the oxides of titanium, zirconium and hafnium for use as high-k materials in microelectronic devices. A carbon-free precursor for the synthesis of hafnium dioxide", Advanced Materials for Optics and Electronics, Vol. 10, 2000, pp. 105-114.
	AW
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	AY
	AZ

Examiner 	Date Considered 11/28/04
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.